

ATTY. DOCKET NO.
006301 USA/
Consilium/Consilium

SERIAL NO.
09/928,474

APPLICANT
Badri N. KRISHNAMURTHY et al.

FILING DATE
August 14, 2001

GROUP
2812

[illegible]

September 16, 2004. International Preliminary Examination Report for PCT Serial No. PCT/US02/24859.

EXAMINER

DATE CONSIDERED

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INFORMATION DISCLOSURE CITATION IN AN APPLICATION (PTO-1449)				ATTY. DOCKET NO. 006301 USA/ Consilium/Consilium		SERIAL NO. 09/928,474	
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<i>CS</i>	4,957,605	09/18/90	Hurwitt et al.			04/17/89	
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EXAMINER <i>Andie C. Hwang</i>			DATE CONSIDERED <i>12/07/04</i>				


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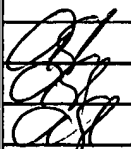








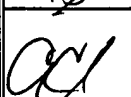

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EXAMINER'S INITIALS	PATENT NO.	DATE	NAME	CLASS	SUBCLASS	FILING DATE	
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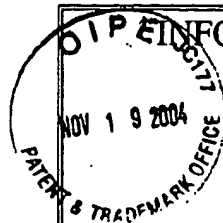
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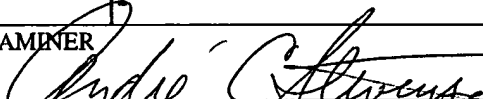
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